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Attorney Docket No. 01017/LH

CERTIFICATE OF MAILING

IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE

Applicant(s): Shinji NAKAHARA et al  
Serial No. : 09/744,363  
Filed : February 21, 2001  
For : EPITAXIAL GROWTH FURNACE  
Art Unit : 1763  
Examiner : K. A. Moore

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231 on the date noted below.

*Yolanda Usher*  
Yolanda Usher

Dated: November 6, 2002

In the event that this Paper is late filed, and the necessary petition for extension of time is not filed concurrently herewith, please consider this as a Petition for the requisite extension of time, and to the extent not tendered by check attached hereto, authorization to charge the extension fee, or any other fee required in connection with this Paper, to Account No. 06-1378.

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AMENDMENT

Commissioner for Patents  
Washington, D.C. 20231

S I R :

This is responsive to the Office Action mailed May 9, 2002, the term for response to which is extended by three months by Petition filed concurrently herewith to November 9, 2002.

IN THE SPECIFICATION

Please replace paragraph [0015] with the following:

In accordance with a preferred aspect of the present invention, the opening flange of the wafer holder comes into contact only with the whole chamfered tapered face of the border of a semiconductor wafer on the side of its surface which is subject to epitaxial growth. The opening flange can also support the wafer through the contact with the tapered face without allowing the slipping out of the wafer to its surface side; in this case, the opening flange does not contact

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